

POWERED BY **Dialog****SURFACE-TREATING DEVICE (08-001065****Publication Number:** JP 8001065 A) , January 09, 1996**Inventors:**

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Applicants

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Application Number: 06-141636 (JP 94141636) , June 23, 1994**International Class (IPC Edition 6):**

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- B05C-005/02
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- H01L-021/306

JAPIO Class:

- 14.7 (ORGANIC CHEMISTRY--- Coating Material Adhesives)
- 42.2 (ELECTRONICS--- Solid State Components)

JAPIO Keywords:

- R011 (LIQUID CRYSTALS)

Abstract:

PURPOSE: To provide a surface-treating device of a simple structure without increasing the device cost and setting space, supplying processing fluids separately to a substrate and enabling a versatile treating of the substrate.

CONSTITUTION: A couple of slits 54b for supplying liquid resists of a different kind on the surface of a glass substrate 16 are formed at the lower end of the slit nozzles 54 of a spin coater, and a uniaxial loader 18 for moving the nozzle 54 parallel with the substrate 16 surface and a driving mechanism 60 to rotate the nozzle 54 around a horizontal rotating shaft 59 are formed. The liquid resins of a different kind are supplied respectively from a couple of resist sources 52 and 62. Accordingly, various liquid resists corresponding to the kind of the substrate 16 and the kind of the process to be applied on the substrate are appropriately supplied on the substrate surface only by directing the any one of the slit selected from the couple of slits 54b to the substrate 16.

JAPIO

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